

3/26/04

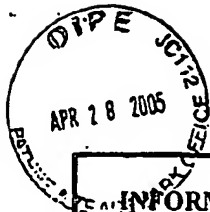
SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811449 Not Yet Assigned		
		APPLICANT Jim Dunphy, et al.				
		FILING DATE Herewith		GROUP Not Yet Assigned		
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
De	U.S. Pub App No. 2003/0002019	1/2/03	Miller			_____
	U.S. Pub App No. 2002/0056898	5/16/02	Lopes, et al.			_____
	U.S. Pub App No. 2002/0063322	5/30/02	Robbins, et al.			_____
	6,300,294	10/9/01	Robbins, et al.			_____
	5,694,740	12/9/97	Martin, et al.			_____
	5,936,758	8/10/99	Fisher, et al.			_____
	5,610,438	3/11/97	Wallace, et al.			_____
De	5,512,374	4/30/96	Wallace, et al.			_____
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						YES
						<input type="checkbox"/> YES <input type="checkbox"/> NO
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
De	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247 Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13					
	"Optimization of Lubricants for silica Micromotors" Zarnd, Sensors and Actuators A 46-47 (1995) 598-600					
	"Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233					
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	"Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE 0-7803-298-5-6, pgs 91-98					
	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269					
	"Stiction reduction processes for surface micromachines" Roya Maboudian Tribology letters 3 (1997) 215-221					
	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353					
	"Measurement of Micromotor Dynamics in Lubricating Fluids" Deng IEEE					
De	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147					
EXAMINER			DATE CONSIDERED 6/2/05			

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INFORMATION DISCLOSURE CITATION APR 28 2005 PTO-1449 SHEET 1 OF 2			ATTY. DOCKET NO.		SERIAL NO.			
			P132-US		10/811,449			
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DL	5,939,785	8/17/99	Klonis, et al.			---		
	5,411,769	8/17/99	Hornbeck			---		
	6,204,085	3/20/01	Strumpell, et al.			---		
	2003/0064149	4/3/03	Miller			---		
	6,259,551	7/10/01	Jacobs			---		
	5,447,600	9/5/95	Webb			---		
	6,300,294	10/9/01	Robbins, et al.			--- duplicated		
	6,086,726	7/11/00	Renk, et al.			---		
	6,475,570	11/5/02	Jacobs			---		
	2004/0100677	5/27/04	Huibers, et al.			---		
DL	2004/0125346	7/1/04	Huibers			---		
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	DL	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICKION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
		W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKION COATINGS FOR MEMS, Pgs 1-6.						
		W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISTANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.						
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Dle	2004/0012838	1/22/04	Huibers	f	f	---	
	2004/0100594	5/27/04	Huibers, et al.			---	
	2004/0156090	8/12/04	Patel, et al.			---	
	5,835,256	11/10/98	Huibers			---	
	6,046,840	4/4/00	Huibers			---	
	6,844,959	1/18/05	Huibers, et al.			---	
	6,867,897	3/15/05	Patel, et al.			---	
	5,287,096	2/15/94	Thompson, et al.			---	
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